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## Application Number

10/617.321

**Filing Date**

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**First Named Inventor**

Choi et al.

## Group Art Unit

2834

**Examiner Name**

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Attorney Docket Number

PA88/UTS-39-05D09

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Feldman et al., "Wafer Chuck for Magnification correction in X-ray Lithography," *Journal of Vacuum Science and Technology*, Nov/Dec 1998, pp. 3476-3479, vol. B 16(6).

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